

9900/2879

**TECH CENTER 2800** 

### E UNITED STATES PATENT AND TRADEMARK OFFICE

THU.		
Applicant:	TSUTOMU YAMADA ET AL.	)
Cardal NI		) Group Art Unit: 2879
Serial No.	09/748,470	) ) Examiner: K. Ramsey
Filed:	December 26, 2000	)
		)
For:	DEPOSITION MASK AND MANUFACTURING	RECEIVED
	METHOD THEREOF, AND	)
	ELECTROLUMINESCENCE DISPLAY AND	MAY 26 2004
	MANUFACTURING METHOD THEREOF	) MAI 20 2004

### **LETTER TO PATENT OFFICE**

Mail Stop Petition Commissioner of Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sirs:

Attached to this Letter is a Petition to Withdraw the Holding of Abandonment. The Petition to Withdraw the Holding of Abandonment was submitted on February 5, 2004 and was received by the patent office on February 9, 2004 (see attached copy of return receipt postcard). It does not appear as if the Petition has been entered by the patent office. Applicant respectfully requests that this Petition be entered.

Respectfully submitted,

**CANTOR COLBURN LLP** 

Lisa A. Bongiovi

Registration No. 48,933

CANTOR COLBURN LLP

55 Griffin Road South

Bloomfield, CT 06002

Telephone (860) 286-2929

Facsimile (860) 286-0115

Customer No. 23413

May 20, 2004 .

MAN 2 4 2004
THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: TSUTOMU YAMADA ET AL.
) Group Art Unit: 2879

Serial No. 09/748,470
) Examiner: K. Ramsey

Filed: December 26, 2000

For: DEPOSITION MASK AND MANUFACTURING METHOD THEREOF, AND ELECTROLUMINESCENCE DISPLAY AND MANUFACTURING METHOD THEREOF

MANUFACTURING METHOD THEREOF
)

TECHCENTER 28000

### PETITION TO WITHDRAW HOLDING OF ABANDONMENT UNDER 37 C.F.R. § 1.181(a)

Mail Stop Petition Commissioner of Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sirs:

In response to the Notice of Abandonment dated January 13, 2004, Applicants submit this Petition to Withdraw Holding of Abandonment under 37 C.F.R. §1.181(a). Consideration and withdrawal of the holding of abandonment are requested.

I hereby certify that this correspondence was deposited with the United States Postal Service as first class mail in an envelope addressed to: Mail Stop Petition, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on

February 5, 2004
(Date of Deposit)

Patricia A. Hart

Name on Person Mailing Japer)

### REMARKS

In the Notice of Abandonment dated January 13, 2004 the present application is indicated as being abandoned for failure to timely file a proper reply to the Office letter mailed on June 19, 2003.

Applicants submit that a Response with Amendment in reply to the Office letter dated June 19, 2003 was timely filed on December 18, 2003 with Petition for Extension of Time and proper fee, thus the holding of abandonment is improper and may not be maintained. In this regard, Applicants respectfully submit evidencing materials as Attachments 1 and 2.

### Attachment 1:

Attached is a copy of the Response with a certification of mailing stating the date of deposit as December 18, 2003 in compliance with 37 CFR 1.8. All the information with regard to the instant application are correctly represented in the cover page of the Response.

### Attachment 2:

Attached is a copy of the return postcard with a stamp of the Office showing that the Office has received the Amendment/Response to Office Action, Petition, and fee with regard to the extension of time.

The documentary evidence discussed herein and submitted herewith clearly establishes that Applicants timely filed a Response on December 18, 2003 to the Office letter dated June 19, 2003. Considering that the date of Office's stamp appeared in the return postcard is December 22, 2003, and the mail date of Notice of Abandonment is January 13, 2004, it is assumed that the Notice was issued before the Response was forwarded to the Examiner.

Accordingly, Applicants herein petition to withdrawal the helding of abandonment set forth in the Notice of Abandonment dated January 13, 2004. Pursuant to MPEP § 711.03(c)I, no fee is required for the present Petition. However if there are any charges due with respect to this Petition or otherwise, please charge them to Deposit Account No. 06-1130 maintained by Applicants' attorneys.

For at least the reasons set forth herein above, the holding of Abandonment is improper and may not be maintained; withdrawal thereof and consideration of the Amendment, dated December 18, 2003 is respectfully requested.

The Examiner is invited to contact Applicants' attorneys at the below-listed telephone number regarding this Petition or otherwise concerning the present application.

Respectfully submitted,

CANTOR COLBURN LLP

Lisa A. Bongiovi

Registration No. 48,933

. CANTOR COLBURN LLP

55 Griffin Road South

Bloomfield, CT 06002

Telephone (860) 286-2929

Facsimile (860) 286-0115

Customer No. 23413

February 5, 2004

## **ATTACHMENT 1**

### COMBINED AMENDMENT & PETITION FOR EXTENSION OF Docket No. TIME UNDER 37 CFR 1.136(a) (Large Entity) YKI-0060 In Re Application Of: Tsutomu Yamada Serial No. Filing Date Examiner Group Art Unit 09/748,470 December 26, 2000 K. Ramsey 2879 Invention: DEPOSITION MASK AND MANUFACTURING METHOD THEREOF, AND JMINESCENCE DISPLAY AND MANUFACTURING METHOD THEREOF TO THE COMMISSIONER FOR PATENTS: This is a combined amendment and petition under the provisions of 37 CFR 1.136(a) to extend the period for filing a The requested extension is as follows (check time period desired): One month ☐ Two months ☑ Three months ☐ Four months ☐ Five months September 19, 2003 December 19, 2003 until: MAY 26 2004 **TECH CENTER 2800** The fee for the amendment and extension of time has been calculated as shown below: **CLAIMS AS AMENDED** CLAIMS REMAINING HIGHEST# NUMBER EXTRA ADDITIONAL RATE : :. AFTER AMENDMENT PREV. PAID FOR CLAIMS PRESENT FEE **TOTAL CLAIMS** 6 20 0 \$18.00 \$0.00 INDEP, CLAIMS 3 0 \$86.00 \$0.00 \$0.00 FEE FOR AMENDMENT \$950.00 FEE FOR EXTENSION OF TIME TOTAL FEE FOR AMENDMENT AND EXTENSION OF TIME 950

### COMBINED AMENDMENT & PETITION FOR EXTENSION OF INTERNITY AND AMENDMENT & PETITION FOR EXTENSION OF INTERNITY AND AMENDMENT & PETITION OF

Docket No. YKI-0060



RECEIVED

MAY 26 2004

The	fee for the amendment and extension of time is to be paid as follows:	TECH CENTER 2800
	A check in the amount of \$950.00 for the amendment and exte	nsion of time is enclosed.
×	Please charge Deposit Account No. 06-1130 in the amount of	\$950.00
X	The Director is hereby authorized to charge payment of the following feet communication or credit any overpayment to Deposit Account No.	s associated with this
	<ul><li>△ Any additional filing fees required under 37 C.F.R. 1.16.</li><li>△ Any patent application processing fees under 37 CFR 1.17.</li></ul>	
	If an additional extension of time is required, please consider this a petition fees which may be required to Deposit Account No.	on therefor and charge any additional

Signature Signature

Dated: December 18, 2003

Lisa A. Bongiovi Reg. No. 48,933 Cantor Colburn LLP 55 Griffin Road South Bloomfield, CT 06002 Telephone (860) 286-2929 Facsimile (860) 286-0115

Customer No. 23413

I certify that this document and fee is being deposited on 12/18/2003 with the U.S. Postal Service as first class mail under 37 C.F.R. 1.8 and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Signature of Person Mailing Correspondence

Agatha Skierkowski

Typed or Printed Name of Person Mailing Correspondence

MAY 2 4 2004 THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	TSUTOMU YAMADA	)
Serial No.	09/748,470	Group Art Unit: 2879
	,	Examiner: K. Ramsey
Filed:	December 26, 2000	) )
For:	DEPOSITION MASK AND MANUFACTURING	)
	METHOD THEREOF, AND	RECEIVED
	ELECTROLUMINESCENCE DISPLAY AND	)
	MANUFACTURING METHOD THEREOF	) MAY 26 2004

**AMENDMENT** 

TECH CENTER 2800

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed December 19, 2003, Applicant requests reconsideration in view of the following remarks for entry in the above-identified application.

I hereby certify that this correspondence is being Mailed via First Class Mail to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450

Agatha Skierkowski

signature

### AMENDMENT TO THE CLAIMS:

1-5. (Canceled)

6. (Original) A method for manufacturing a deposition mask, wherein said deposition mask for placing between a depositing material and a medium on which deposition is performed comprises a semiconductor substrate including an opening forming region having a reduced thickness provided with at least one opening for allowing said depositing material to be selectively attached to a desired position on said medium, and a thick portion formed in at least one portion of a mask outer periphery region of said semiconductor substrate.

said method comprising the steps of:

forming a first coating covering a region in which said thick portion of said semiconductor substrate is to be formed;

using said first coating as an etching mask to etch said semiconductor substrate so as to reduce thickness of said semiconductor substrate and thereby form said opening forming region;

forming a second coating in areas other than a predetermined position within said opening forming region; and

using said second coating as an etching mask to etch said semiconductor substrate so as to form said at least one opening in said predetermined position.

- 7. (Currently Amended) A method for manufacturing a deposition mask as defined in Claim 6, wherein said semiconductor substrate is composed of silicon.
- 8. (Currently Amended) A method for manufacturing a deposition mask manufacturing method as defined in Claim 6, wherein

said first coating is formed on a first side of said semiconductor substrate;

said opening forming region is formed by etching said first side of said semiconductor substrate to reduce thickness of said substrate;

said second coating is formed on a second side of said semiconductor substrate; and said at least one opening is formed by etching from said second side until penetrating through said semiconductor substrate.

9-13. (Canceled)

14. (New) A deposition mask to be placed between a material source and a medium which is a deposition target, comprising:

a plurality of opening forming regions having a plurality of openings for allowing a depositing material to be selectively attached to a desired position on said medium; and

a thick portion formed in an area between said plurality of opening forming regions and on an outer periphery region of said mask, wherein

each of said plurality of opening forming regions has a thickness which is less than that of said thick portion.

15. (New) A deposition mask as defined in Claim 14, wherein said plurality of opening forming regions correspond to a plurality of display panel regions to be formed on said medium.

16. (New) A deposition mask as defined in Claim 14, wherein said area between said plurality of opening forming regions in which said thick portion is formed corresponds to a gap position between pixels of a display panel to be formed on said medium.

. . .

#### REMARKS

Claims 1-13 are pending in the application. Claims 1-5 and 9-13 have been canceled, claims 14-16 have been added, and claims 6 and 7 have been amended, leaving claims 6-8 and 14-16 for consideration upon entry of the present amendment. Support for the new claims is found throughout the detailed description of the preferred embodiment. Applicant respectfully requests reconsideration in view of the amendment and remarks submitted herewith.

Claims 1-5 stand rejected under 35 U.S.C. § 102(b) as being anticipated by Staples (U.S. 4,013,502). Because claims 1-5 have been canceled, this rejection is moot.

Claims 1-8 stand rejected under 35 U.S.C. § 102(b) as being anticipated by Mauger (U.S. 4,966,663). "A claim is anticipated only if each and every element as set forth in the claim is found, either expressly or inherently described, in a single prior art reference." Verdegaal Bros. V. Union Oil Co. of California, 814 F.2d 628, 631, 2 USPQ2d 1051, 1053 (Fed. Cir. 1987). Moreover, "[t]he identical invention must be shown in as complete detail as is contained in the \* \* \* claim." Richardson v. Suzuki Motor Co., 868 F.2d 1226, 1236, 9 USPQ2d 1913, 1920 (Fed. Cir. 1989).

Claims 6-8 include the following limitation: "forming a first coating covering a region in which said thick portion of said semiconductor substrate is to be formed; using said first coating as an etching mask to etch said semiconductor substrate so as to reduce thickness of said semiconductor substrate and thereby form said opening forming region."

Accordingly, these limitations require formation of an opening in the thin portion. Mauger does not disclose this limitation.

In Mauger, there is no opening, and thus, the substrate cannot be used as a deposition mask. It is clear that Mauger does not presume the use of the silicon substrate as a mask. In addition, Mauger fails to disclose or even suggest formation of an opening in the thin portion after the thin portion is formed, as required by the claims.

In order to form an opening forming region by reducing a thickness of a semiconductor substrate as described in the present invention, a long etching time is required. In the present invention, after an opening forming region is formed through a process that requires a long etching time, an opening is formed through the substrate in a predetermined position on the opening forming region. Thus, after an opening is formed, the opening that requires a high precision in the shape is not exposed to a process for reducing the thickness of the substrate, such as that applied in the opening forming region that requires a long time for etching. Mauger, which fails to disclose formation of an opening, cannot anticipate reducing the thickness of the substrate and then forming an opening, and thus it is clear that claim 6

cannot be anticipated by Mauger. Moreover, formation of a deposition mask through steps as in the present invention cannot be viewed as obvious from Mauger.

Thus, Mauger does not anticipate claim 6. In addition, because claims 7 and 8 include all of the limitations of claim 6, Mauger does not anticipate claims 7 and 8. Accordingly, Applicant respectfully requests that the rejection be withdrawn.

In addition claims 6-8 are also allowable over Staples. Staples discloses a use of silicon wafer as a stencil in a process that uses a molecular beam method. As described in Figure 1 (Figs. 1a-1g) and corresponding description (Col. 3), the manufacturing procedure of the stencil in Staples is (a) forming a groove on the front side of a wafer in a portion that will become an opening of a mask (Fig. 1d) and (b) then etching only a central region of the wafer from the back side of the wafer (Figs. 1e and 1f).

Staples, which discloses a use of a wafer as a stencil (mask), still fails to disclose or even suggest reducing the thickness of a substrate to form an opening forming region and then forming an opening, as described in claim 6 of the present invention. Thus, it is clear that it is not obvious for a person with ordinary skill in the art to first reduce the thickness of a substrate (or form a thick portion at least on a peripheral region of a mask) and then form an opening. In Staples, because the opening is formed first, the opening is exposed to a process for reducing the thickness of the substrate such as in the opening forming region that requires a long etching time, after the opening if formed, which results in an expansion of the size of the opening during the process for reducing the thickness of the substrate. Therefore, with the process of Staples, it is not possible to form an opening with a high precision as in the present invention. In addition, Staples does not recognize the necessity to employ the steps as described in the present invention.

In addition, Applicant has added claims 14-16. None of the citations discloses a thick peripheral portion of a mask, that the thickness is reduced in a region in which an opening is to be formed, that a thick portion is provided in a region between a plurality of opening formation regions, and that the mask is reinforced by the thick portion and the thick peripheral region of the mask. By providing a thick portion in the central region of the mask in addition to the peripheral region, it is possible to maintain the strength of the mask even when a large semiconductor mask substrate is used for a large medium, and, at the same time, to maintain a thin thickness for the opening forming region and a high positional precision of the opening. None of the citations discloses or even suggests such a mask and has no description of necessity of the mask. Accordingly, Applicant respectfully requests that claims 14-16 be allowed.

In view of the foregoing, it is respectfully submitted that the instant application is in condition for allowance. Accordingly, it is respectfully requested that this application be allowed and a Notice of Allowance issued. If the Examiner believes that a telephone conference with Applicant's attorneys would be advantageous to the disposition of this case, the Examiner is cordially requested to telephone the undersigned.

In the event the Commissioner of Patents and Trademarks deems additional fees to be due in connection with this application, Applicant's attorney hereby authorizes that such fee be charged to Deposit Account No. 06-1130.

Respectfully submitted,

CANTOR COLBURN LLP

Lisa A. Bongiovi Registration No. 48,933

CANTOR COLBURN LLP

55 Griffin Road South

Bloomfield, CT 06002

Telephone (860) 286-2929

Facsimile (860) 286-0115

Customer No. 23413

December 18, 2003

AND TRADEMARK OFFICE IN THE UNITED STATES PATENT

Applicant:

TSUTOMU YAMADA

Serial No.

09/748,470

Filed:

December 26, 2000

For:

DEPOSITION MASK AND MANUFACTURING

METHOD THEREOF, AND

ELECTROLUMINESCENCE DISPLAY AND MANUFACTURING METHOD THEREOF

RECEIVED

Group Art Unit: 2879

Examiner: K. Ramsey

MAY 26 2004

LETTER TO EXAMINER

**TECH CENTER 2800** 

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

For your information, this application is related to Application Serial No. 09/966,692, which was filed on September 28, 2001. Along with this letter, Applicant is filing an Information Disclosure Statement that lists all of the art currently cited in Application Serial No. 09/966,692. However, because the present application was filed before Application Serial No. 09/966,692, all of that art may not necessarily be prior art references.

Respectfully submitted,

CANTOR COLDURN LLP

Lisa A. Bongiovi

Registration No. 48,933

CANTOR COLBURN LLP

55 Griffin Road South Bloomfield, CT 06002

Telephone (860) 286-2929

Facsimile (860) 286-0115

Customer No. 23413

December 18, 2003

YKI-0060 09/748,470

### INFORMATION DISCLOSURE STATEMENT

TECHCENTER 2890

														90-	
ΔΤΤΌ Γ	DOCKE	TNUMB	FR '	XKI-0060	SER	IAL I	NUMB	R 09	/74	8,47	0_FI	LED 3	12/2	26/20	00
		OR: <u>T.</u>			- TI	TLE	DEPOS	ITION	M	ASK A	ND ]	MANU	FAC	TURI	1G
METHO		EREOF,	AND	ELECTRO											
METHO		EREOF	444	EXAMINER							ART	UNI	7 28	379	
				-											
	submitted	for considera	tion by t	opy of (a) attache he Office; (b) a leg	lible cop	y of eac	n docume	nt required t	Dy 31	Ç.F.R. 9	1.30(0)(2	.).			
	filing date	under 35 U.S	S.C. §120	ent Office of referer    The Serial Num  entitled	ber of th	ie parer	it applicati	on is U.S. A	ppiica	illon					<del></del>
	are not re	quired. 🗖 A	dditiona	re listed on attache I parent patent ap	olications	s are lis	ted on an	attached sne	eel						
3. 🗆	D Acc	nov of a transl	ation of	1.98(a)(3), Applica	nalish d	locumer	es that for nt, or porti	each refere on thereof, is	ence r s prov	ot in Eng rided here	ish (che with;	ck at le	ast on	e box bei	ow):
	□ p	rovided in the	accomp	(check at least of anying foreign or in	temation	nai sear		•		to the spe	cification	ı; and/or	☐ bro	vided here	with.
37 C.F.R.	§1.97(b)(1	), (b)(2) - Wi	THIN 3 I	MONTHS OF FILI	NG OR I	ENTRY	IN NATIO	NAL STAG	Ε	-616		lination		in thron mo	antho
4.	of the dat §1.97(e)	e of entry of the s required.	he natior	re Statement is bei nal stage as set for	th in 37	C.F.R. §	1.491 in a	in internation	nai ap	рисацон,	no lee c	n cerunc	auonu	ilidei 37 C	.F.fX.
37 C.F.R.	§1.97(b)(3	), (b)(4) – PRI	ORTON	IAILING OF FIRST	OFFICE	ACTIO	NOR FIRS	TACTION A	AFTE	RREQUE	STFOR	CONTI	NUED	EXAMINA'	TION
5.	Since this of a first (	Information	Dicclosu	re Statement is be filing of a request	ing filed	hefore	the mailing	date of the	e first (	Office Act	ion on tr	e ments	, or be	rore the ma	alling
37 C.F. R	. §1.97(c)	- AFTER FIR	ST ACT	ION, BEFORE FI	NAL AC	TION O	R ALLOV	ANCE							
6. <b>a</b> . b.	Since this of a Final	s Information     Rejection or   fee required	Disclosu Notice o under 37	re Statement is be of Allowance, this: 'C.F.R. §1.97(c)(2 n 37 C.F.R. §1.97	ing filed submissi () and sp	outside ion is be secified	of the per sing according 37 C.F.	riod provided apanied by ( R. §1.17(p).	(one	n 37 C.F.f of the fol	R. §1.97 lowing l	(b), but t coxes n	etore t	ne mailing e checked	):
	24.07(1)		A) DE	CCTION OF ALL	THANC	=									
37 C.F.R. 7. 🗀	Since this fee and in be chec	s Information I s accompanie ked.)	Disclosu ed by bot	ECTION OR ALL re Statement is be th the statement sp	ing filed becified i	after the in 37 C.	F.K. §1.91	(e) and the	iee s	et forth in	3/ U.F.	r. 91.11	(p). (E	10X 0 UI 3	Illusi
8. 🗅	Stateme	nt was first cite	ed in anv	§1.97(e)(1), Applic communication for Disclosure Statem	om a fore	eion pate	ent office if	i a counterba	an tot	eign appi	ication r	ot more	man m	ation Discl ree months	osure s prìor
9.	Stateme	nt was cited in	a com	§1.97(e)(2), Appli nunication from a naking reasonable a 37 C.F.R. §1.56(	foreign p	atent of	fice in a co	ounterpart to ion containe	oreign ad in t	application	on, and, nation Di	sclosure	State	ge of the p ment was k	ICI SUIT
10. 😭	In the evapplicati	ent the Comr on, Applicant	nissione 's attorn	er of Patents deem eys authorize that	s that ar such fee	ny additi e be cha	onal fee is rged to De	required un eposit Accou	inder unt N	37 C.F.R. 0. <u>06-11</u>	§§ 1.16 .30	or 1.17	in con	nection wi	th this
11. Cor	nsideratior	of this Inform	nation Di	isclosure Stateme	nt is resp	oectfully	requeste	i.							
N	lame: L	isą A.	Вог	ngiovi				Regist	tration	Number	48	,933	<u> </u>		
	nature	HU	بر	Bons	\ <u>\</u>			Date	D	ecem	ber	18,	20	03	
sufficien	nt postage a	s first class ma	il in an ei	ISSION: I hereby convelope addressed to ark Office to Facsim	о: Сотт	this corr issioner	espondenc For Palent	s, P.O. Box 1	1450, i	d with the Alexandria ate shown	, VA 223	ates Pos 13-1450,	tal Serv or [ ] f	rice with acsimile	
				erkowski		<i>~</i> ,									
<b> </b>	Taine .	A LIIA	٠٨٦	0 // 4		1)			T	<b></b>	1	- 10		002	$\neg$
Sign	nature	JATT	للا	U/C		<u> </u>		Date		Dece:	mber	. тя	, 2	2003	

YKI-0060 Applicant(s) INFORMATION DISCLOSURE CALL Yamada et al. (Use several sheets if necessary) Group Art Unit Filing Date

App..camou ii Docket Number (Optional) 09/748,470

			MAY 2 4 2004	U.S. PATENT	DOCUMENTS		avmer 4 50	FILING DATE	$\neg$
MINER	REF	DOCUMENT NUMBER	DATE		NAME	CLASS	SUBCLASS	# APPROPRIATE 8/21/1995	-
TIAL		5,641,611	6/24/1997	Shieh et al.		438	35		
		5,900,339	5/4/1999	Roberts et	al.	430	7	11/21/1997	
		6,087,274	7/11/2000	Tonucci et	al.	438	758	3/3/1998	
		6,165,543	12/26/2000	Otsuki et a	d.	427	66	6/14/1999	
		US 6,214,631 B1	4/10/2001	Burrows e	t al.	438	22	10/30/1998	
			7/3/2001	Ikuko et a	l.	313	506	5/14/1998	
	-	US 6,255,775 B1	7/9/2002	Kitazume	et al.	438	160	4/30/2001	
	ļ	US 6,417,034 B2	10/1/2002	Fukuzaw	a et al.	313	402	10/21/1999	
·· -	-	US 6,459,193 B1	10/1/2002	Kido et a	 l.	313	504	5/14/1997	
9 1984 		US 6,459,199 B1	1/24/2002	Arai		427	66	5/3/2001	
٠	<del></del>	US 2002/0009538 A1	1/24/2000						
<u> </u>				FOREIGN	PATENT DOCUME	NTS			
			2177	10222	COUNTRY	CLASS	SUBCLASS	Translat YES	no NO
	REI	DOCUMENT NUMBER	DATE			-	PECEIV	ED	
							RECEIVE	ond	
								1 1	
							TECH CENTE	R 2809	
							_		
5,5 ,765						i i tushan Ti	ide Date Pertine	nt Pages, Etc.)	
<del></del>				OTHER	DOCUMENTS (In	20, 2002.			
		Office Action for A	pplication Serial	140. פרועט 140. פרועט	me union 110 rounds	-			
						003			
-14-		Office Action for A	application Serial	No. 09/966,69	2, dated June 24, 2	.003.			

EXAMINER

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. Patent and Trademark Office \* U.S. DEPARTMENT OF COMMERCE

Form PTO-A820 (also form PTO-1449)



# RECEIVED

MAX SE SOOD

TECH CENTER 2000

		CANTOR COLBURN LLP  VENDORID PTO Commissioner of Patents and NUMBER NAVOIGE NUMBER INVOICE DATE INVOICE AMOUNT PREVIOUS PAYCREDIT NVOICE AMOUNT PREVIOUS PAYCREDIT
IOIAL		38828  ACCOUNT#  DISCOUNT TAKEN
	******180.00	TE 12/18/03 AMOUNT OF PAYMENT

Commissioner of Patents and CANTOR COLBURN LLP Trademark Office One Hundred Eighty & 00/100 Dollars O Fleet 12/18/03 \*\*\*\*\*\*180.00

""B'1EET B9100 :1125005110:1 ""B2BBEO"

# **ATTACHMENT 2**



THE STAMP OF THE PATENT OFFICE, PLACED HEREON, ACKNOWLEDGES RECEIPT OF:

Attorney Docket: YKI-0060

Date Mailed: 12/18/2003

Applicant: Tsutomu Yamada et al.

Date Filed: 12/26/2000

09/748,470 For: DEPOSITION MASK AND MANUFACTURING METHOD THEREOF, AND ELECTROLUMINESCENCE DISPLAY AND

MANUFACTURING METHOD THEREOF

Combined Amendment Transmittal and Petition for Extension of Time with Certificate of Mailing by First Claus, Mail (2 pgs), Amendment (6 pgs), Letter to the Examiner (1 pg), Transmittal of IDS with Certificate of Mailing by First Class Mail (1 pg), PTO Form 1449 (1 pg), Citations (12) and Check in the amount of \$180.00 for the IDS filing fee

Received in the USPTO on:

REGENVED

WAY 28 200M

TECH CENTER 28,009



### RECEIVED

MAY 26 2004

TECH CENTER 2800

THE STAMP OF THE PATENT OFFICE, PLACED HEREON, ACKNOWLEDGES RECEIPT OF:

Attorney Docket No.: YKI-0060 Date Mailed: February 5, 2004 Applicant: Tsutomu Yamada et al.

Serial No.: 09/748,470 Filed: December 26, 2000

For: DEPOSITION MASK AND MANUFACTURING METHOD THEREOF, AND ELECTROLUMINESCENCE DISPLAY AND

MANUFACTURING METHOD THEREOF

Petition to Withdraw Holding of Abandonment Under 37 C.F.R.

§1.181(a) with Attachments (186 pages); Post Card Receipt

Mailed via First Class Mail to USPTO on: February 5, 2004

Received in the USPTO on:

CERTIFICATE OF I		Docket No.				
Applicant(s): Tsutomu Y	Yamada et al.			YKI-0060		
Serial No.	Filing Date	Examiner		Group Art Unit		
09/748,470	December 26, 2000	K. Ramsey		2879		
057710,170	05/746,470 December 20, 2000 IX. Ramsey					
Invention: <b>DEPOSITIO</b>	N MASK AND MANUFACTURI	ING METHOD THEREOF, A	ND ELE	CTROLUMINESCENCE		
DISPLAY AND MANUFA	CTURING METHOD THEREO	F				
IPE				wen_		
10. 40			1	RECEIVED MAY 26 2004		
MAY 2 4 2004 15				26 2004'		
				MAY 20 20		
PROPERTY OF THE PROPERTY OF TH				TECH CENTER 2800		
I hereby certify that this	S Letter to the Patent Office wi	th Attachments		1EOu a		
to the transfer of the decidence	''	(Identify type of correspondence)		olone addropped to:		
is being deposited wi	ith the United States Postal Se	ervice as first class mail in	an enve	siope addressed to.		
Commissioner for Pate	ents, P.O. Box 1450, Alexandria,	VA 22313-1450 on		20, 2004		
			(	(Date)		
		Patricia A	Hart >	1		
		(Typed of Printed Name of Person		orrespondence		
			/ {/	$\sim 1$		
	-	(Signature of Person Mailin	g Correspo	ondence)		
	Note: Each paper must ha	ve its own certificate of mailing.				
i				1		